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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/790,792	03/03/2004	Sang-cheol Ko	102-1019	4382
38209 STANZIONE &	7590 06/14/2007 & KIM. LLP	EXAMINER		
919 18TH STREET, N.W.			ELVE, MARIA ALEXANDRA	
SUITE 440 WASHINGTON, DC 20006			ART UNIT	PAPER NUMBER
			1725	
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			06/14/2007	PAPER

Please find below and/or attached an Office communication concerning this application or proceeding.

The time period for reply, if any, is set in the attached communication.

		Application No.	Applicant(s)		
Office Action Summary		10/790,792	KO ET AL.		
		Examiner .	Art Unit		
		M. Alexandra Elve	1725		
Period fo	The MAILING DATE of this communication app or Reply	ears on the cover sheet with the c	orrespondence address		
A SH WHIC - Exter after - If NO - Failu Any (ORTENED STATUTORY PERIOD FOR REPLY CHEVER IS LONGER, FROM THE MAILING DANSIONS of time may be available under the provisions of 37 CFR 1.13 SIX (6) MONTHS from the mailing date of this communication. Period for reply is specified above, the maximum statutory period were to reply within the set or extended period for reply will, by statute, reply received by the Office later than three months after the mailing and patent term adjustment. See 37 CFR 1.704(b).	ATE OF THIS COMMUNICATION 36(a). In no event, however, may a reply be timution and will expire SIX (6) MONTHS from a cause the application to become ABANDONE.	I. nely filed the mailing date of this communication. D (35 U.S.C. § 133)		
Status					
2a)⊠	Responsive to communication(s) filed on <u>27 March 2007</u> . This action is FINAL . 2b) This action is non-final. Since this application is in condition for allowance except for formal matters, prosecution as to the merits is				
	closed in accordance with the practice under E	x parte Quayle, 1935 C.D. 11, 45	63 O.G. 213.		
Dispositi	on of Claims				
5)□ 6)⊠ 7)□	Claim(s) 1,2,4 and 6-27 is/are pending in the a 4a) Of the above claim(s) 23-27 is/are withdraw Claim(s) is/are allowed. Claim(s) 1,2,4 and 6-22 is/are rejected. Claim(s) is/are objected to. Claim(s) are subject to restriction and/or	n from consideration.	·		
Applicati	on Papers				
10)⊠	The specification is objected to by the Examiner The drawing(s) filed on <u>03 March 2004</u> is/are: a Applicant may not request that any objection to the Replacement drawing sheet(s) including the correction The oath or declaration is objected to by the Example 1.	a)⊠ accepted or b)□ objected to drawing(s) be held in abeyance. See ion is required if the drawing(s) is obj	e 37 CFR 1.85(a). ected to. See 37 CFR 1.121(d).		
Priority (ınder 35 U.S.C. § 119				
 12) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f). a) All b) Some * c) None of: 1. Certified copies of the priority documents have been received. 2. Certified copies of the priority documents have been received in Application No. 3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)). * See the attached detailed Office action for a list of the certified copies not received. 					
Attachmen	t(s)				
1) Notice 2) Notice 3) Inform	te of References Cited (PTO-892) te of Draftsperson's Patent Drawing Review (PTO-948) mation Disclosure Statement(s) (PTO/SB/08) r No(s)/Mail Date	4) Interview Summary Paper No(s)/Mail Da 5) Notice of Informal P 6) Other:	nte		

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DETAILED ACTION

Election/Restrictions

Newly submitted claims 23-27 are directed to an invention that is independent or distinct from the invention originally claimed for the following reasons: new claims are directed towards etching a first surface that is different than the heating unit location and the separation of a plurality of ink jet heads.

Since applicant has received an action on the merits for the originally presented invention, this invention has been constructively elected by original presentation for prosecution on the merits. Accordingly, claims 23-27 are withdrawn from consideration as being directed to a non-elected invention. See 37 CFR 1.142(b) and MPEP § 821.03.

Claim Rejections - 35 USC § 112

Claims 7 & 15 rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention, that is, "cleaning an organic material having flown onto the wafer".

Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

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(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claims 1-2, 4, 6-7, 9 & 15-22 are rejected under 35 U.S.C. 103(a) as being unpatentable over Richerzhagen (USPN 5,902,499) in view of Yamamoto et al. (USPN 5,482,660), Merdan et al. (USPN 6,696,666) and Peng et al. (USPN 6,737,606).

Richerzhagen discloses a laser and liquid jet for material machining. The system has a processing module (housing) and the workpiece is cut using the laser-liquid jet device. Nd:YAG lasers may be used. Pressures range from about 10 bars to 1000 bars. Nozzles are sizes from 5 to 50um. A conical shape may be used for focusing.

Richerzhagen does not teach the presence of a wafer, or a stage or all types of lasers or the laser beam diameter.

Yamamoto et al. discloses the fabrication of an ink jet head. Side and top-down jets are taught. An excimer laser beam is irradiation on the discharge port face and the stage is moved with the substrate thereon. The substrate may be made of glass, quartz and ceramic.

It would have been obvious to one of ordinary skill in the art at the time of the invention to use a stage and a wafer, as taught by Yamamoto et al. in the Richerzhagen process because the stage enhance versatility during fabrication and the use of a wafer is merely a design choice.

Although the exact pressures and sizes are not taught they are closely approximating or overlapping. It is well settled that where patentability is predicated upon a change in a condition of prior art process, such as pressure or hole size, the

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change must be at least "critical", that is, it must lead to a new and unexpected result.

The applicant has the burden of providing such criticality. Note In re Aller et al. 105

USPQ 223.

Merdan et al. discloses the use of hybrid laser water jet system (laser micro-jet). Types of lasers suitable for use with this system are YAG lasers, IR lasers, CO2 lasers, diode lasers and any combination thereof. (col. 2, lines 28-39, 65-67; col. 5, lines 12-17, 30-36)

It would have been obvious to one of ordinary skill in the art at the time of the invention to use different types of lasers as taught by Merdan et al. because this is drawn to the same liquid jet guided laser.

Peng et al. discloses the use of laser beam liquid assembly for the dicing of wafers. The liquid stream has a diameter equal to the laser beam diameter, which is about 50 to 150 μ m. (col. 2, lines 19-23, 53, 60-62; col. 7, lines 22-27)

It would have been obvious to one of ordinary skill in the art at the time of the invention to note the diameter as taught by Peng et al. because these parameters are based on the same liquid jet guided laser.

Claims 8 & 10-14 are rejected under 35 U.S.C. 103(a) as being unpatentable over Richerzhagen, Yamamoto et al., Merdan et al. and Peng et al., as stated in the above paragraph and further in view of Hashimoto et al. (USPAP 2004/0246292).

Richerzhagen does not teach dicing of a wafer.

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Hashimoto et al. discloses separation of a silicon wafer in the manufacturing a of ink jet head. It would have been obvious to one of ordinary skill in the art at the time of the invention to dice a wafer, as taught by Hashimoto et al. in the Richerzhagen system because it is merely a specific type of laser and liquid jet material machining.

Response to Arguments

Applicant's arguments filed 3/27/07 have been fully considered but they are not persuasive.

Applicant argues that Richerzhagen does not disclose an ink jet print head. The examiner respectfully notes that Richerzhagen teaches the use of a liquid jet guided laser for machining, while Yamamoto et al. teaches the fabrication of an ink jet head. In response to applicant's arguments against the references individually, one cannot show nonobviousness by attacking references individually where the rejections are based on combinations of references. See *In re Keller*, 642 F.2d 413, 208 USPQ 871 (CCPA 1981); *In re Merck & Co.*, 800 F.2d 1091, 231 USPQ 375 (Fed. Cir. 1986).

Applicant argues that Yamamoto et al. teaches only the use of an excimer laser and not the liquid jet guided laser. the examiner respectfully notes that Richerzhagen teaches the use of a liquid jet guided laser for machining, while Yamamoto et al. teaches the fabrication of an ink jet head using a laser. In response to applicant's arguments against the references individually, one cannot show nonobviousness by attacking references individually where the rejections are based on combinations of

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references. See *In re Keller*, 642 F.2d 413, 208 USPQ 871 (CCPA 1981); *In re Merck* & Co., 800 F.2d 1091, 231 USPQ 375 (Fed. Cir. 1986).

In response to applicant's argument that the examiner's conclusion of obviousness is based upon improper hindsight reasoning, it must be recognized that any judgment on obviousness is in a sense necessarily a reconstruction based upon hindsight reasoning. But so long as it takes into account only knowledge which was within the level of ordinary skill at the time the claimed invention was made, and does not include knowledge gleaned only from the applicant's disclosure, such a reconstruction is proper. See *In re McLaughlin*, 443 F.2d 1392, 170 USPQ 209 (CCPA 1971).

Applicant argues that Merdan et al. is not analogous art and hence is not applicable. The examiner respectfully disagrees because Merdan et al. discloses the use of a hybrid laser water jet system (laser micro-jet) to cut holes in a stent which is much the same as cutting holes for an ink jet. Furthermore, Merdan et al. was used to show that there are many types of lasers suitable for use with this liquid jet system for cutting holes.

In response to applicant's argument that Merdan et al. is nonanalogous art, it has been held that a prior art reference must either be in the field of applicant's endeavor or, if not, then be reasonably pertinent to the particular problem with which the applicant was concerned, in order to be relied upon as a basis for rejection of the claimed invention. See *In re Oetiker*, 977 F.2d 1443, 24 USPQ2d 1443 (Fed. Cir. 1992). In this

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case, Merdan et al. discloses the use of a hybrid laser water jet system (laser micro-jet) to cut holes in a stent which is much the same as cutting holes for an ink jet.

Applicant argues that Peng et al. does not teach an ink jet. The examiner respectfully notes that Peng et al. was used to teach the diameter of the liquid stream through which a laser beam travels prior to machining. In response to applicant's arguments against the references individually, one cannot show nonobviousness by attacking references individually where the rejections are based on combinations of references. See *In re Keller*, 642 F.2d 413, 208 USPQ 871 (CCPA 1981); *In re Merck* & Co., 800 F.2d 1091, 231 USPQ 375 (Fed. Cir. 1986).

Applicant argues that Hashimoto et al. does not teach the limitations of the ink jet fabrication and hence is not applicable art. the examiner respectfully disagrees because Hashimoto et al. was used to teach the dicing of a silicon wafer. In response to applicant's arguments against the references individually, one cannot show nonobviousness by attacking references individually where the rejections are based on combinations of references. See *In re Keller*, 642 F.2d 413, 208 USPQ 871 (CCPA 1981); *In re Merck & Co.*, 800 F.2d 1091, 231 USPQ 375 (Fed. Cir. 1986).

Conclusion

THIS ACTION IS MADE FINAL. Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

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A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the mailing date of this final action.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to M. Alexandra Elve whose telephone number is 571-272-1173. The examiner can normally be reached on 6:30-3:00 Monday to Friday.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Jonathan Johnson can be reached on 5751-272-1177. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

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Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

June 10, 2007.

M. Alexandra Elve

Primary Examiner 1725